

Notice of References Cited	Application/Control No. 10/757,228	Applicant(s)/Patent Under Reexamination SINHA, NISHANT	
	Examiner Christian Wilson	Art Unit 2824	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,306,756	10-2001	Hasunuma et al.	438/632
	B	US-6,487,106	11-2002	Kozicki, Michael N.	365/153
	C	US-6,712,985	03-2004	Biskeborn, Robert Glenn	216/22
	D	US-5,547,902	08-1996	Rohner, Don	438/613
	E	US-5,654,232	08-1997	Gardner, Donald S.	438/661
	F	US-5,610,103	03-1997	Xu et al.	438/800
	G	US-5,668,055	09-1997	Xu et al.	438/637
	H	US-6,306,761	10-2001	Taguchi, Mitsuru	438/646
	I	US-6,245,655	06-2001	Moslehi, Mehrdad M.	438/612
	J	US-6,593,227	07-2003	Ryskoski, Matthew	438/631
	K	US-6,537,903	03-2003	Givens, John H.	438/622
	L	US-6,757,971	07-2004	Sinha, Nishant	29/852
	M	US-5,308,792	05-1994	Okabayashi et al.	438/618

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Hauder <i>et al.</i> , Chemical mechanical polishing of silver damascene structures, <i>Microelectronic Engineering</i> , 64 (2002) 73.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.